Machine Name : Field emission electron microscope

Brand : ZEISS

Machine Model : Sigma 300

Stock No. : 89738

Ex-factory Date : 2013



Main Technical Parameters:

Type of electron source: Schottky thermal field emission
Acceleration voltage: 100 V – 30 kV
Magnification: 12× – 1,000,000×
SEM resolution:
1 nm @ 30 kV
1.5 nm @ 15 kV
2.8 nm @ 1 kV
Electron beam exposure size: 20 nm
Field stitching accuracy:<100 nm
Scanning frequency: 6 MHz
Graphic format: GDSII





PamtonSchnell



